

Re: United States Patent Application No. 10/552,681  
Filing Date: February 28, 2007  
Title: METHOD FOR PRODUCING MULTIPLE LAYER SYSTEMS  
Inventor(s): Meier, Bhullar  
Our Ref.: 007404-000740

Applicants' claim 12 includes the limitation that an intermediate, "sacrificial" layer is used to selectively remove an adjacent non-conductive or metallic layer. In particular, a sacrificial layer (such as an organic polymer layer) is deposited adjacent a dielectric layer and photon energy is introduced into the sacrificial layer to ablate the sacrificial layer and thereby to remove either the non-conductive layer above or the metallic layer below. Applicants believe that that feature is neither taught nor suggested by Wojnarowski.

The pending Office Action appears to contend that Wojnarowski discloses applying energy to a sacrificial layer to remove either a non-conductive layer above or a metallic layer below. In particular, the Office Action appears to contend that Wojnarowski provides a non-conductive layer 76 adjacent an intermediate sacrificial (bi)layer 18/20, and uses laser energy to ablate the intermediate (bi)layer 18/20, thus removing the non-conductive layer 76.

Applicants' review of the Wojnarowski '547 patent suggests that the Wojnarowski non-conductive layer is removed by ablating it directly, and not by the ablation of an adjacent "sacrificial" layer. Wojnarowski discloses a non-conductive layer that overlies a dielectric layer, and Wojnarowski teaches that "[t]he nitride film is removed at the same time and in the same area during the laser ablation of second dielectric layer 20." Wojnarowski '547 at col. 7, lines 60-63. This appears to disclose using a laser to ablate both layers directly, rather than ablating only the intermediate/sacrificial layer and causing the non-conductive layer to be removed as a consequence of that ablation of the dielectric layer.

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